

#5 | 158
3-28-01
R. Stokes

862.C2032

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
HIROSHI TSUJI ET AL.) : Examiner: NYA
Application No.: NYA) : Group Art Unit: NYA
Filed: Herewith) :
For: ELECTRON BEAM) :
LITHOGRAPHY APPARATUS : October 18, 2000

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09/691234
1142C
00/51/01

The Assistant Commissioner of Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under
37 C.F.R. § 1.56 and in accordance with the practice under
37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is
directed to the documents identified on the enclosed Form
PTO-1449. Copies of the documents are also enclosed.

For the concise statement of relevance for the non-
English documents the Examiner is referred to the abstracts
attached thereto.

It is respectfully requested that the above
information be considered by the Examiner and that a copy of

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the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our below listed address.

Respectfully submitted,

Z. P. Diane
Attorney for Applicants

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